

Critical Factors in Testing MRAM Devices

W. Stevenson
Cypress Semiconductor, Inc



Inc.

G. Asmerom
C. Taylor
Electroglas



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AGENDA / OBJECTIVE

- MRAM Device ?
 - Nomenclature, Advantages, Applications
- MRAM Principles ?
 - Logic States, Read Ops, Write Ops
- Testing Challenges ?
 - KGD Test Flow
 - Device Tuning, Stray Mag Fields
 - How overcome?
 - (EG Prober, External Field Control Measures)
- Summary / Conclusions !

MRAM KEY POINTS

- Magnetoresistive Random Access Memory
 - Technology Marriage [CMOS + Mag Spin Layer]
 - DRAM Density
 - SRAM Speed
 - NVRAM Data Retention

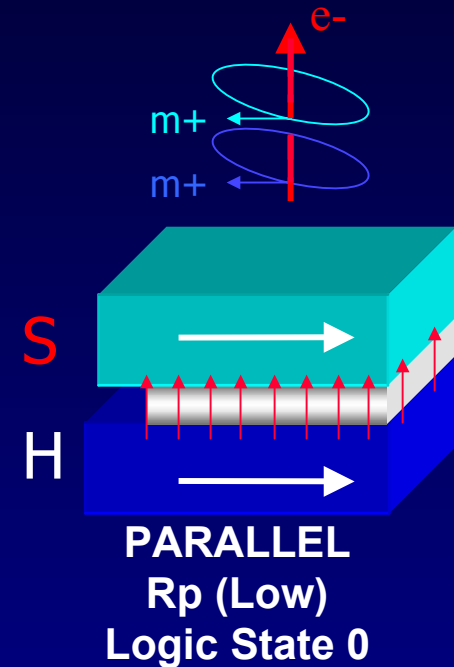
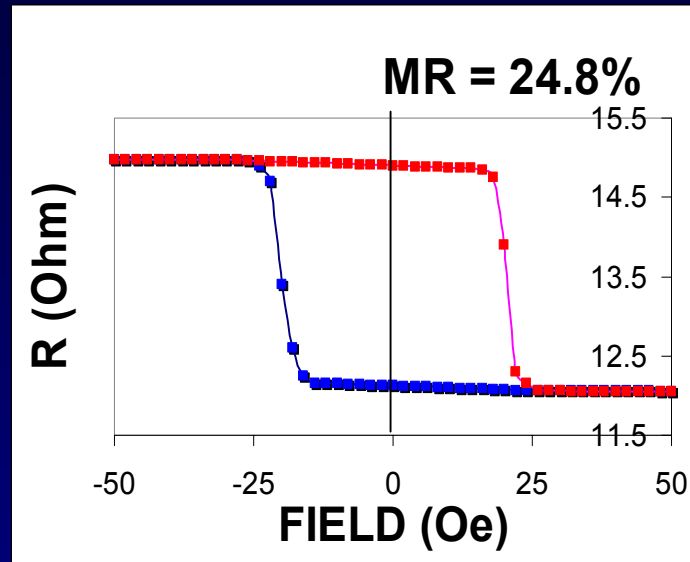
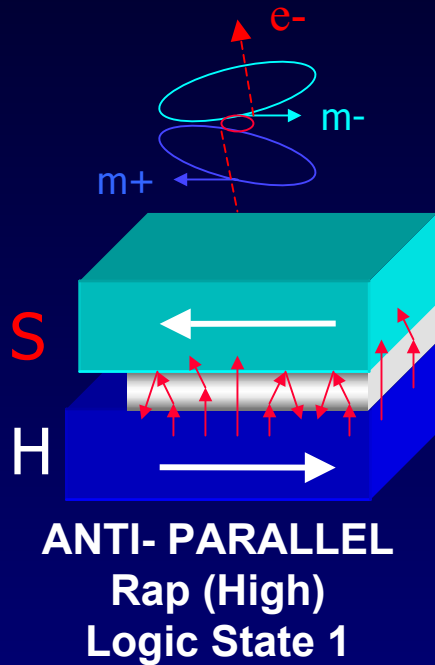
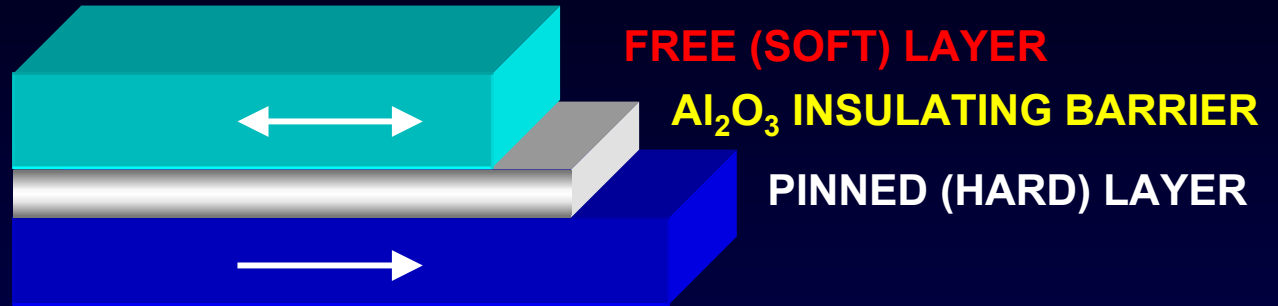
- Key Aspects
 - Competitive Cell Size
 - High Write-cycle Endurance
 - Fast Write/Read Cycles
 - Data Retention Without Standby Power

EMERGING MEMORIES

- Perfect Memory ?
 - Low Cost (dense), Fast Data Access / Write, Low Power, Non-Volatile, CMOS compatible, Reliable
- New Technologies: FRAM, MRAM, OUM
- MRAM = Ideal Choice

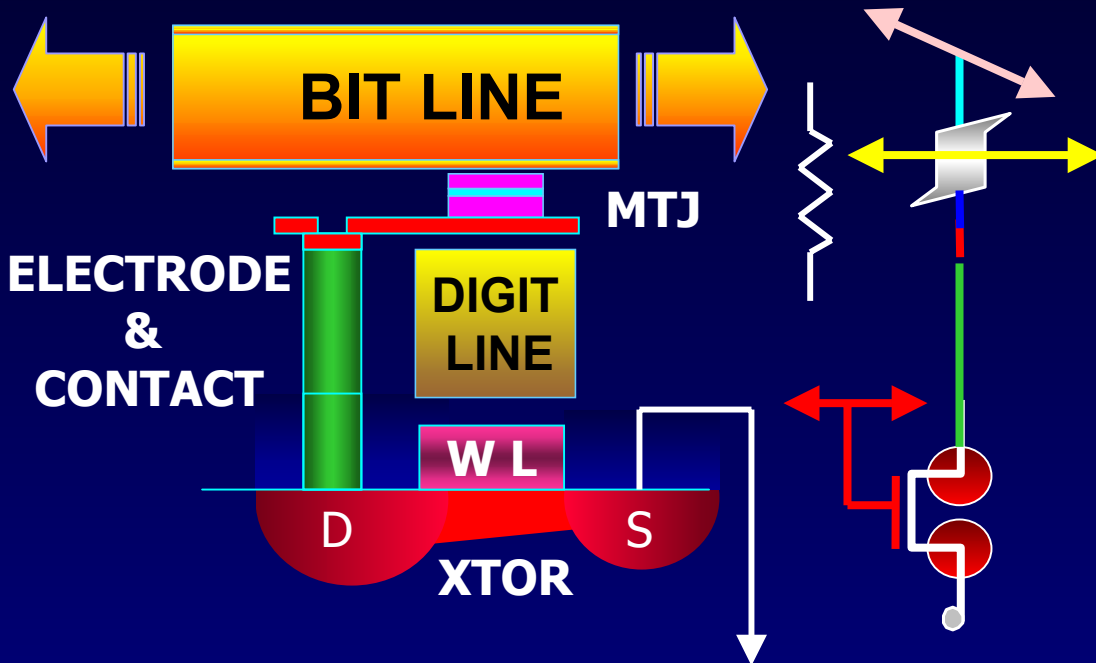
◎ BEST ○ GOOD ● WORST	DRAM	SRAM	FLASH	FRAM	MRAM	OUM
COST	◎	●	○	○	○ / ◎	◎
ACCESS TIME	○	◎	○	○	◎	○
WRITE TIME	◎	◎	○	○	◎	○
ACTIVE POWER	◎	○	●	◎	◎	◎
STANDBY	●	○	◎	◎	◎	◎
NON-VOLATILE	●	●	◎	◎	◎	◎
ENDURANCE	◎	◎	●	○	◎	◎

MTJ – SPINTRONIC STATES

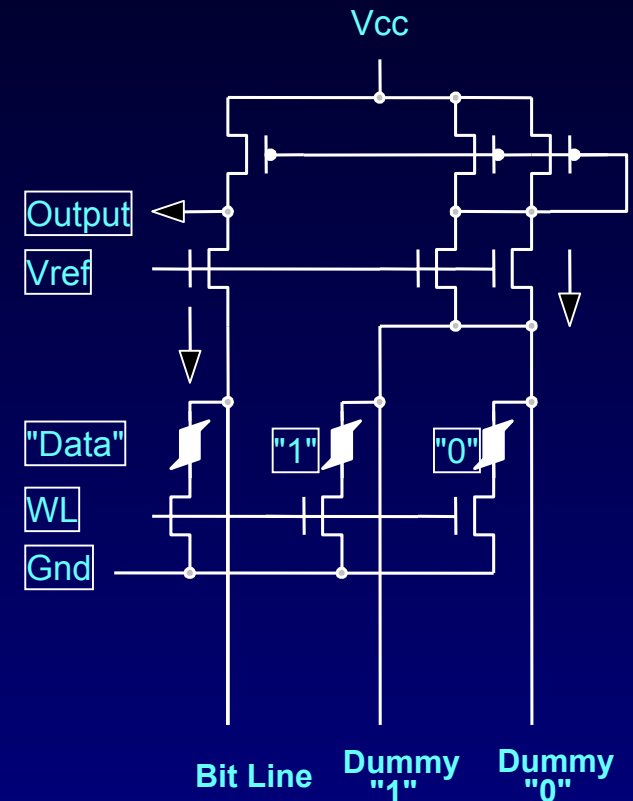


NON-DESTRUCTIVE READ

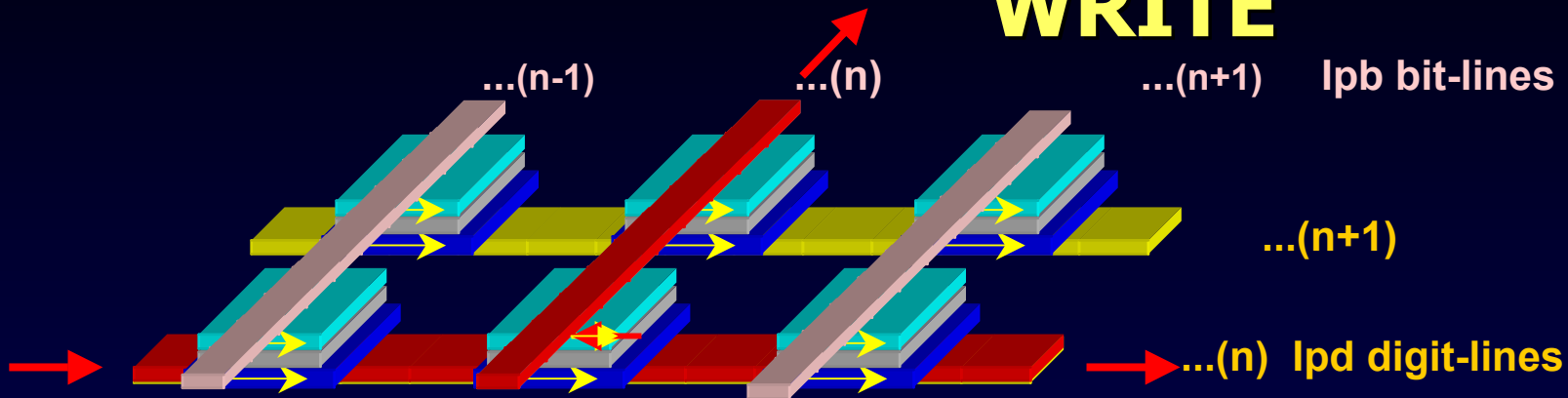
Read Resistance Of
Selected 1T1R



Compare Resistance To
Reference 1T1R*



NON-DESTRUCTIVE WRITE



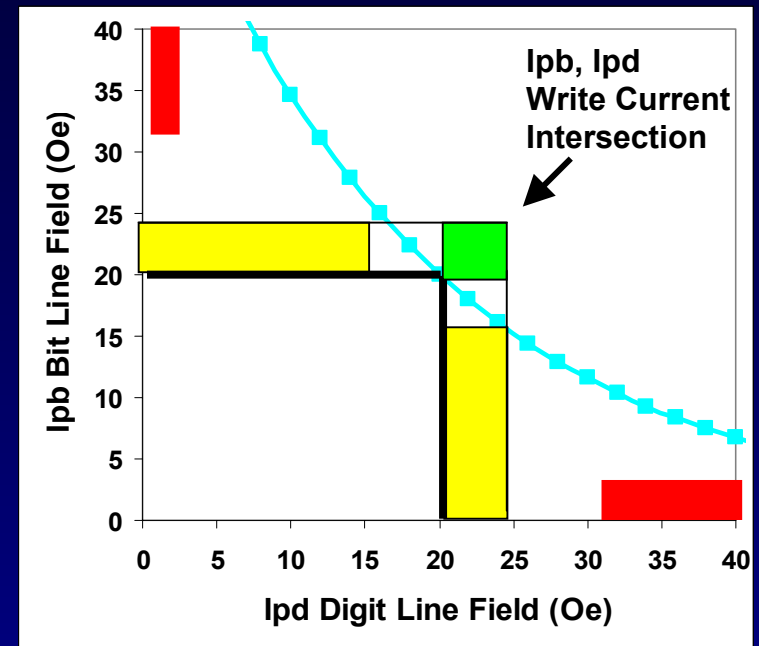
Y Ipb
X Ipd

Ipb => Easy Axis (bitline)

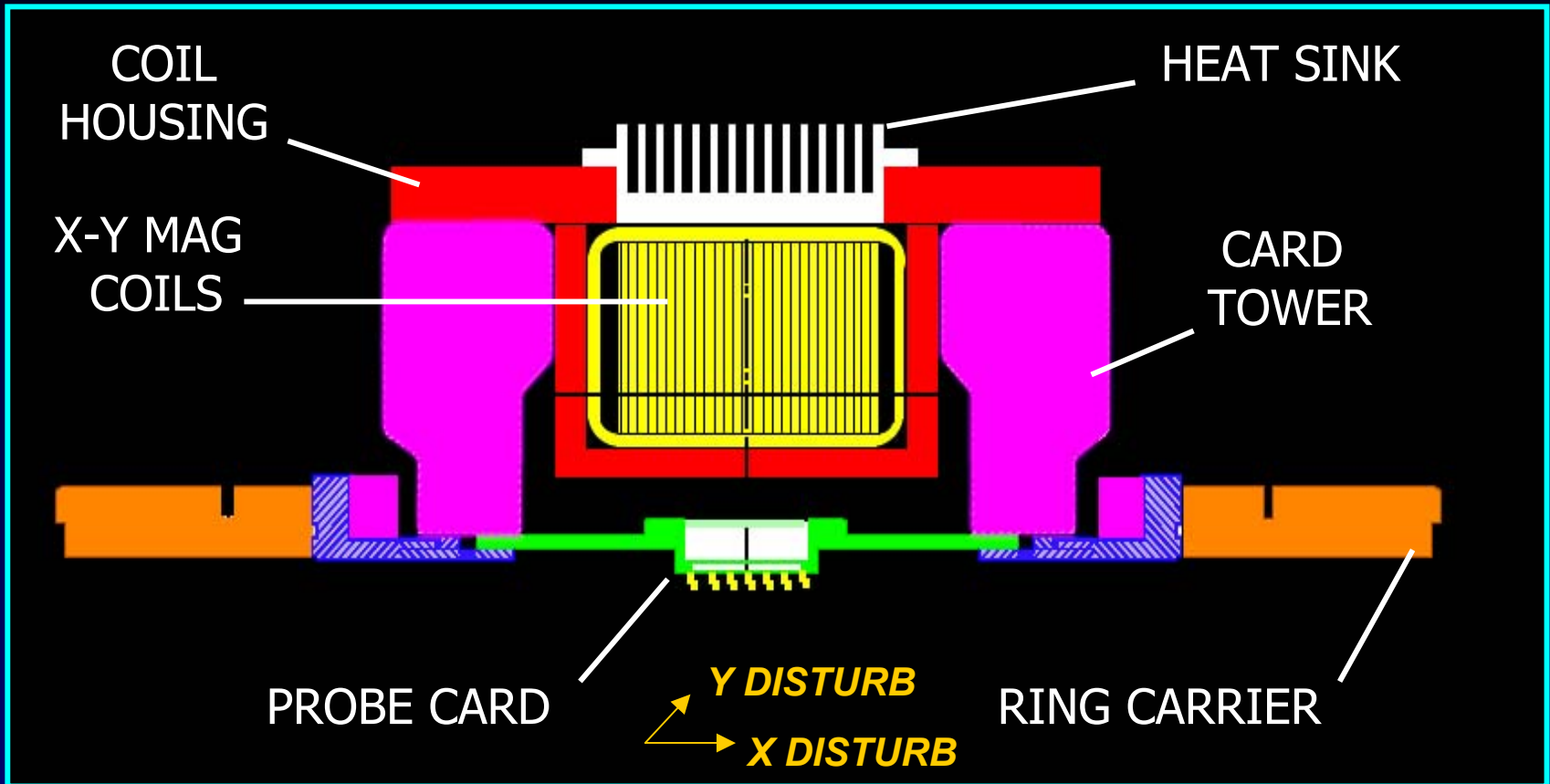
Ipd => Hard Axis (digit line)

Resultant Current = Ipd + Ipb

Only Intersection Gets Full Current



SORT MAG FIELD COILS



- Find Hyper-sensitive Bits –
Sweep External XY Fields to Find > Repair / Kill

TEST CHALLENGES

- Scribeline Test
 - Standard IC tests: Transistor, Resistor, Contact, etc.
 - MRAM Adds Magnetic Switching
- Wafer Sort
 - Testing MRAM Is Similar to Testing SRAM
 - Adds Current Tuning & Disturb Tests at Sort-1
 - (Before Repair & Shielding)
 - Requires a Magnetically Neutral Environment
 - ($< +/-1.0$ Oe)
 - Produces a KGD device (WLBI, Class, etc.)
- Key Challenge
 - Magnetically Neutral Environment for Prober

MEASUREMENT UNITS

- \vec{H} Magnetic Field Strength
 - CGS 1 oersted [Oe] – 2 poles @ 1cm -> 1 dyne
- \vec{B} – Flux Density
 - # Flux Lines Passing Perpendicular to Given Area
 - CGS 1 gauss [G] – 1 flux lines / 1 cm²
 - SI 1 Tesla [T] – 10K flux lines / 1cm²
 - 1 G = 1 Oe in free space (air)
 - Earth's Magnetic Field ~ 0.7 Gauss
 - Total Flux Density is RSS of X, Y, Z components

$$B = \sqrt{B_x^2 + B_y^2 + B_z^2}$$

GAUSSMETERS

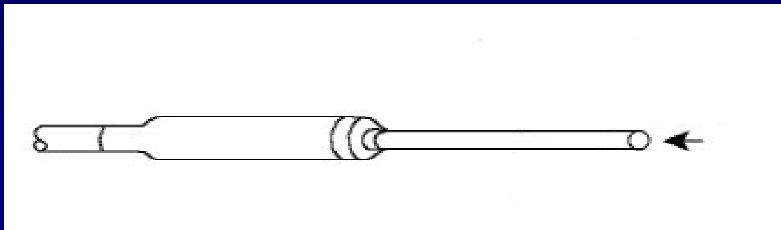
- F.W.Bell 1-axis, 2 Axis
- Lakeshore 2-axis
 - As Easy As Voltmeters
 - Hall Effect Devices



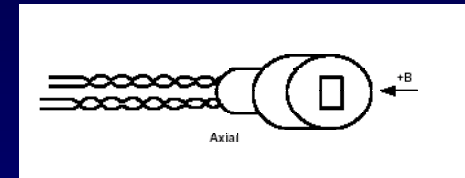
GAUSSMETERS

- Sources of Error
 - Drift - 1 Hour Warm up
 - Zeroing – Null in Zero Flux Chamber $< -.004$ G
 - Positioning – Probe Perpendicular to Surfaces
 - Temperature - Avoid High Temperature Areas
 - Interference – Lab Equipment Audited, Max $< .21$ G

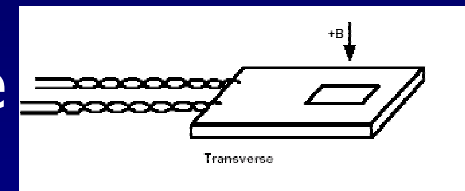
Probe



Axial



Transverse



MAGNETIC FIELD MEASUREMENTS

Engineering the Electroglas 4090 μ Prober for a Neutral Magnetic Environment

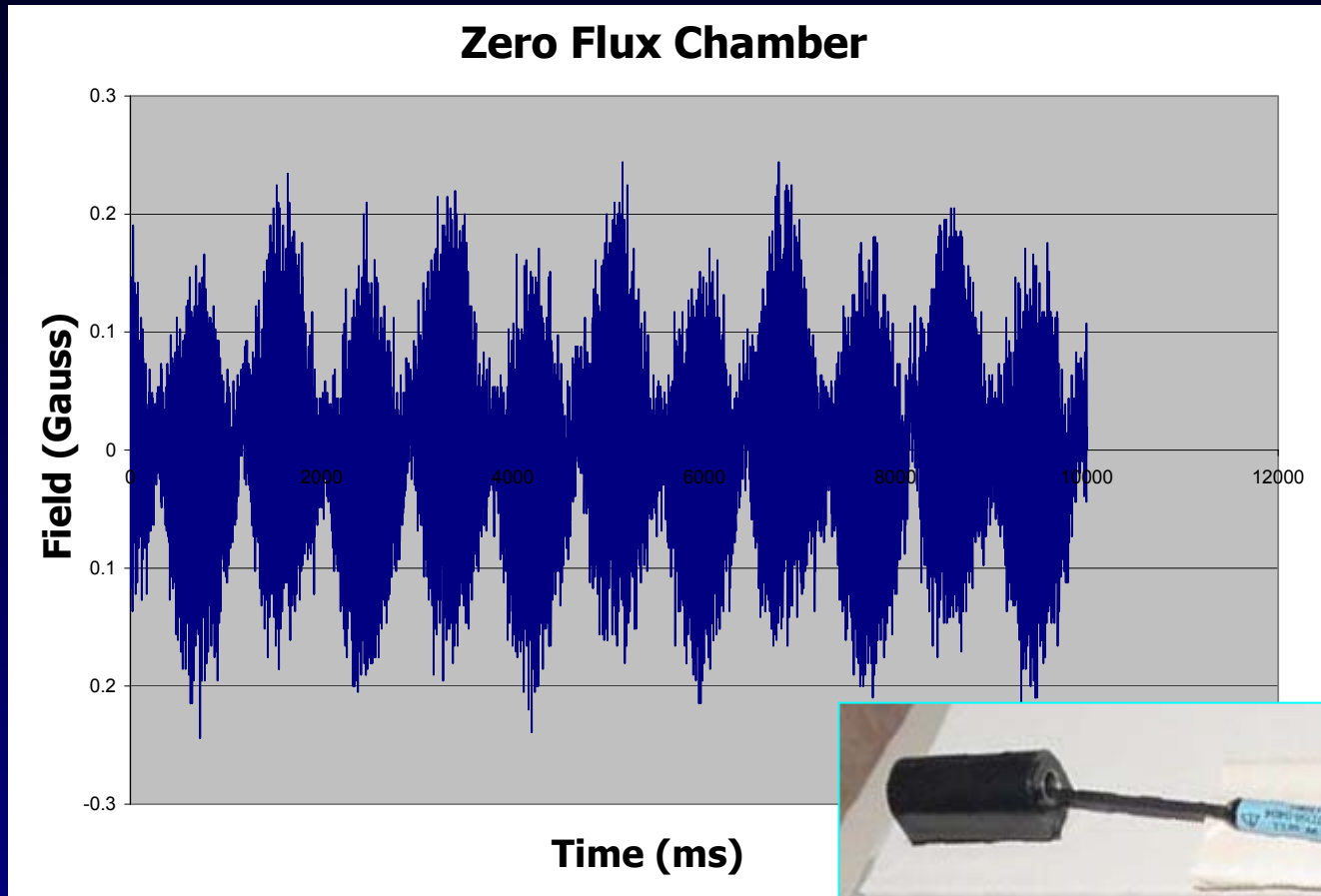
- Dynamic Analysis
 - Gaussmeter Noise
 - Z Motion
 - X,Y Motion
 - Temperature Transition
- Static Analysis
 - Chuck
 - Quick Loader
 - Transfer Arm
 - Pre-aligner
 - Lift Pins

DYNAMIC MEASUREMENTS

- Dynamic Measurements Made at 1000 Hz
- Analog-Out Signal Used
- Data Captured Using Test Point Software

NOISE LEVEL ANALYSIS

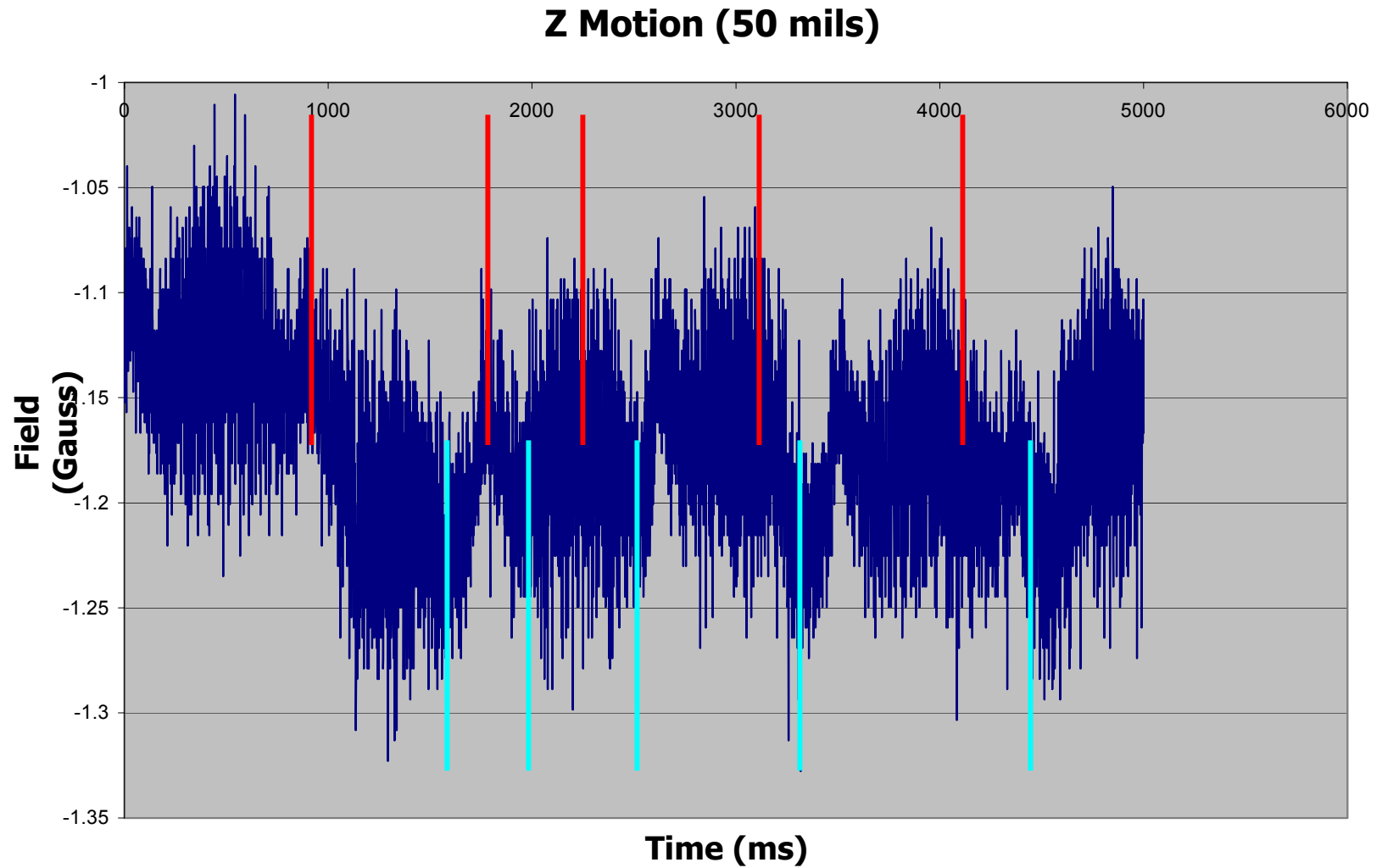
- Measured with probe in zero flux chamber



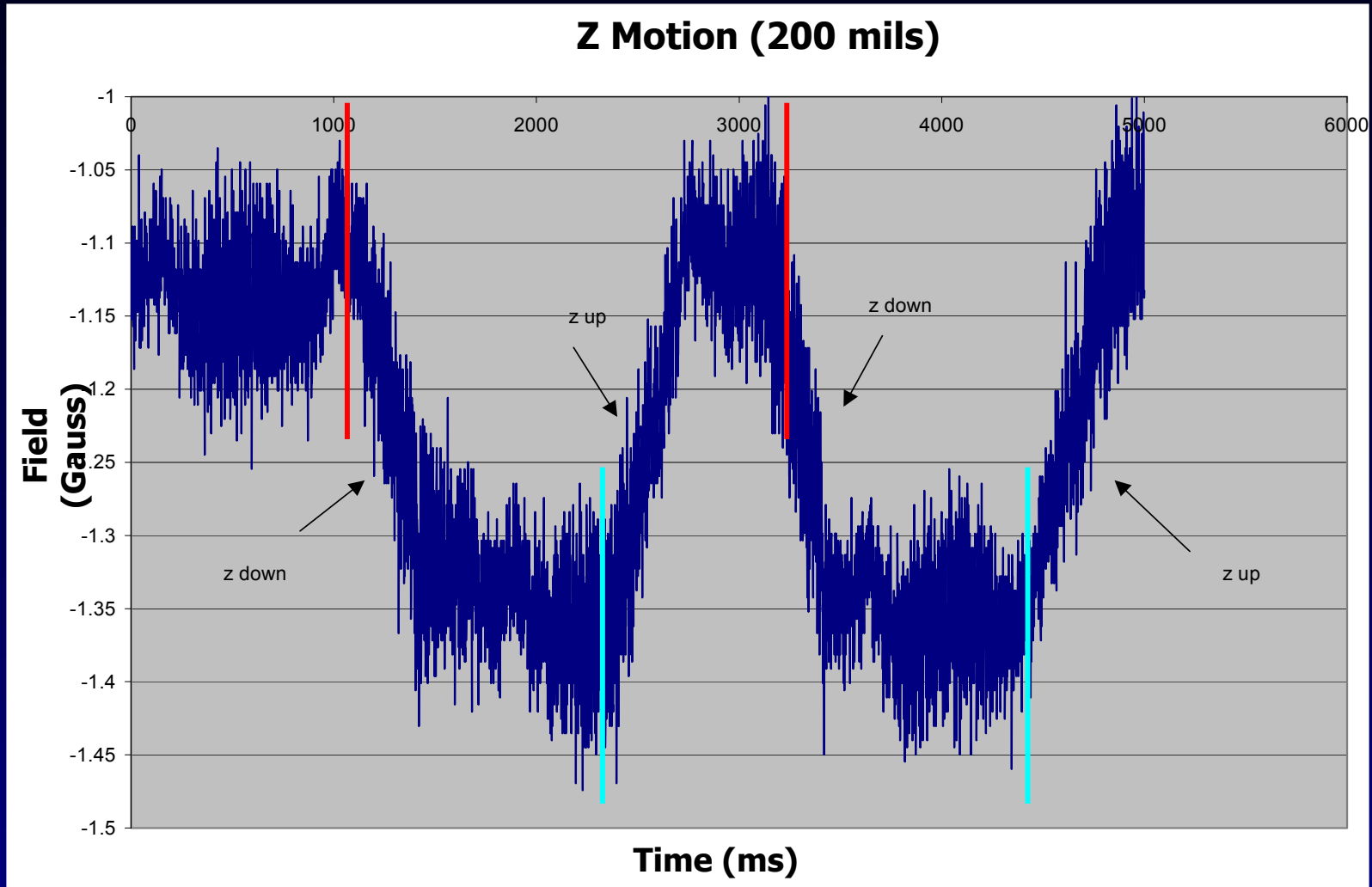
MOTION ANALYSIS

- Probe on Chuck Top (Wafer Plane on Forcer)
 - Proximal to Vacuum Pin
 - Field Component Normal to the Chuck Top
- Measurements Made for Z Motions:
 - 5 Mils, 10 Mils, 20 Mils
 - 50 Mils, 200Mils – Data Shown
- Measurements Made for XY Platen Motions:
 - X-fast, X-slow, Y-fast, Y-slow
- Measurements Made for Temperature Change:
 - Ambient to Hot (25C to 125C) Peltier

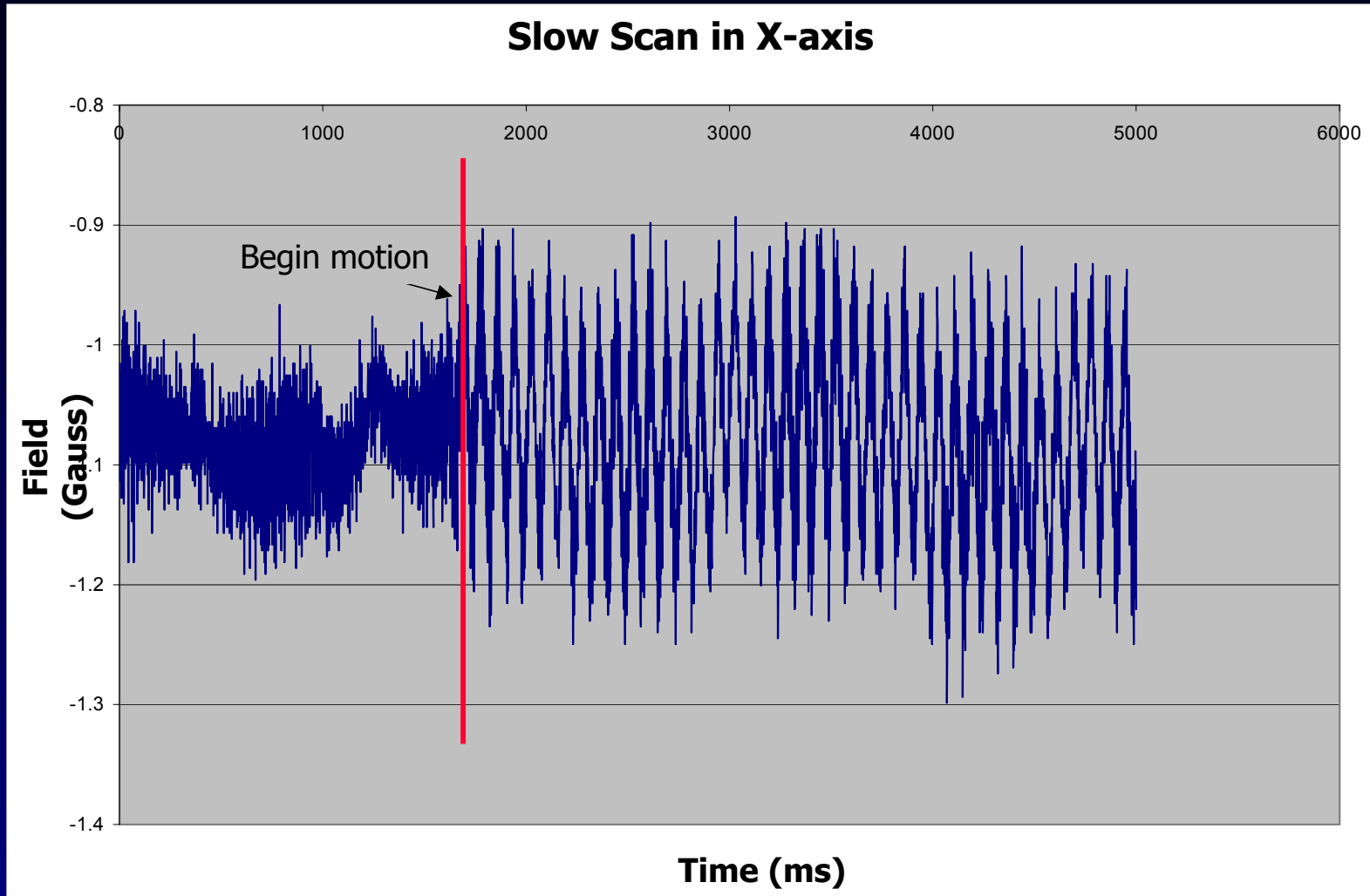
Z MOTION DATA – 50 MILS



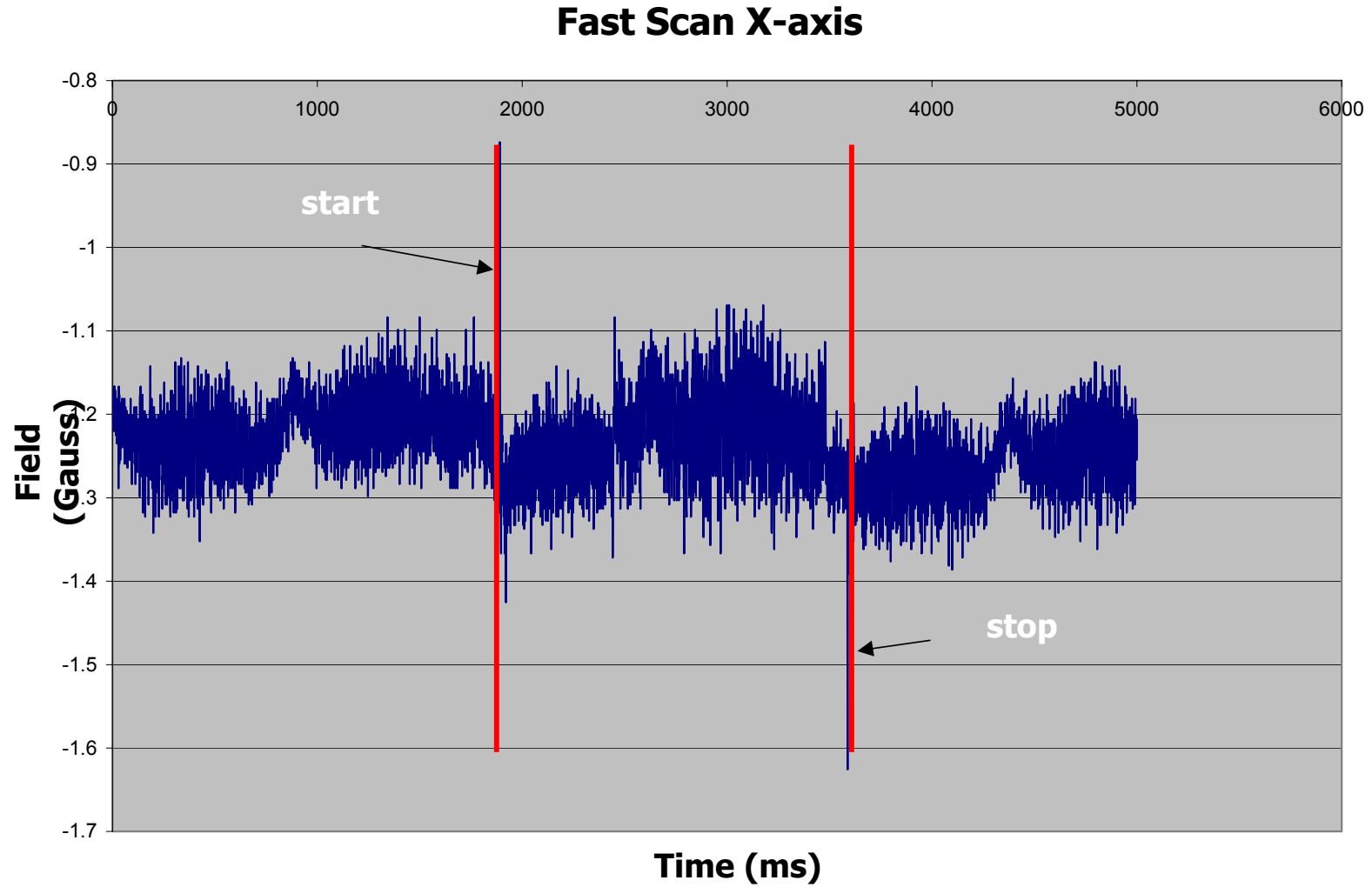
Z MOTION DATA – 200 MILS



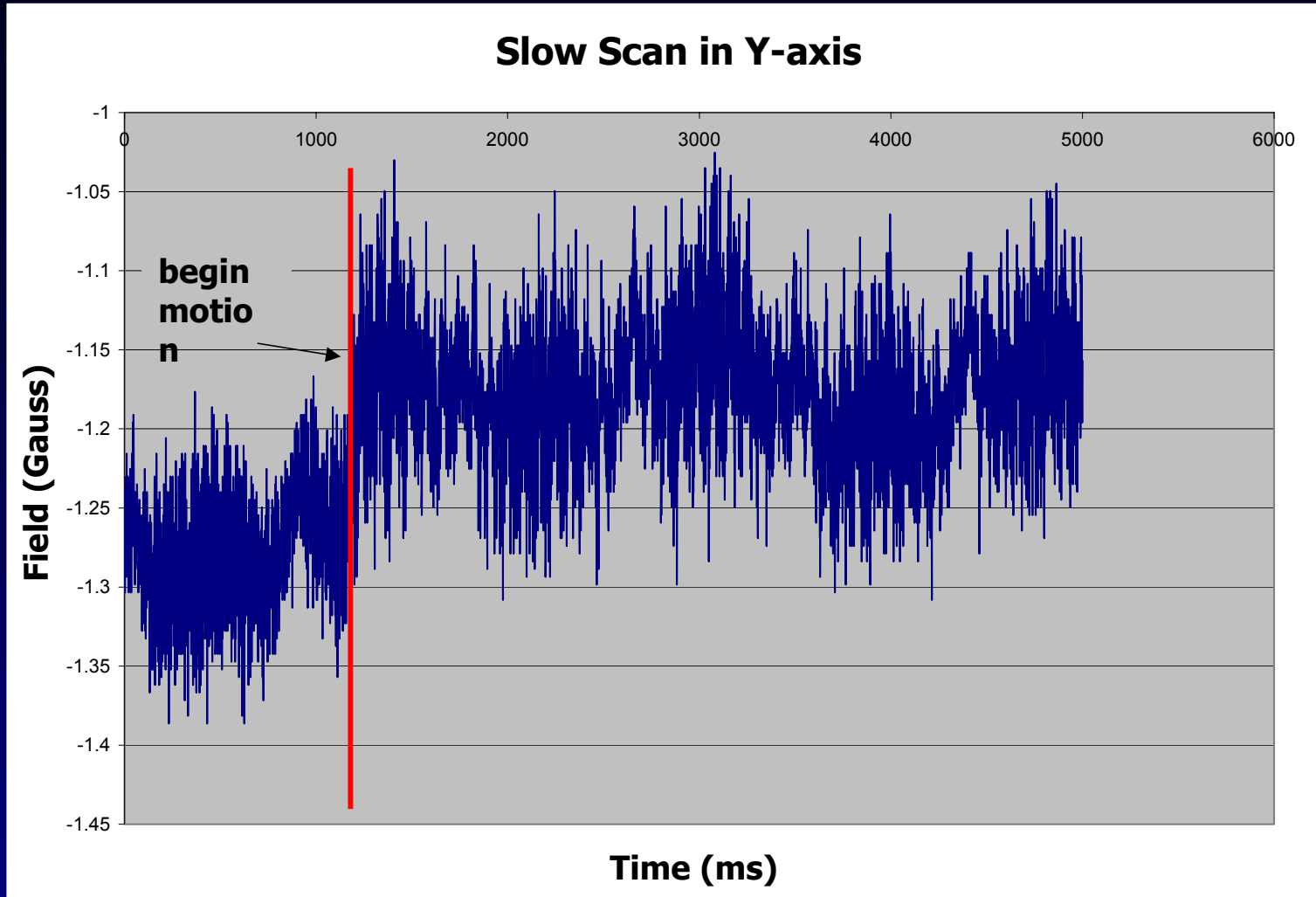
X MOTION SLOW SCAN



X MOTION FAST SCAN

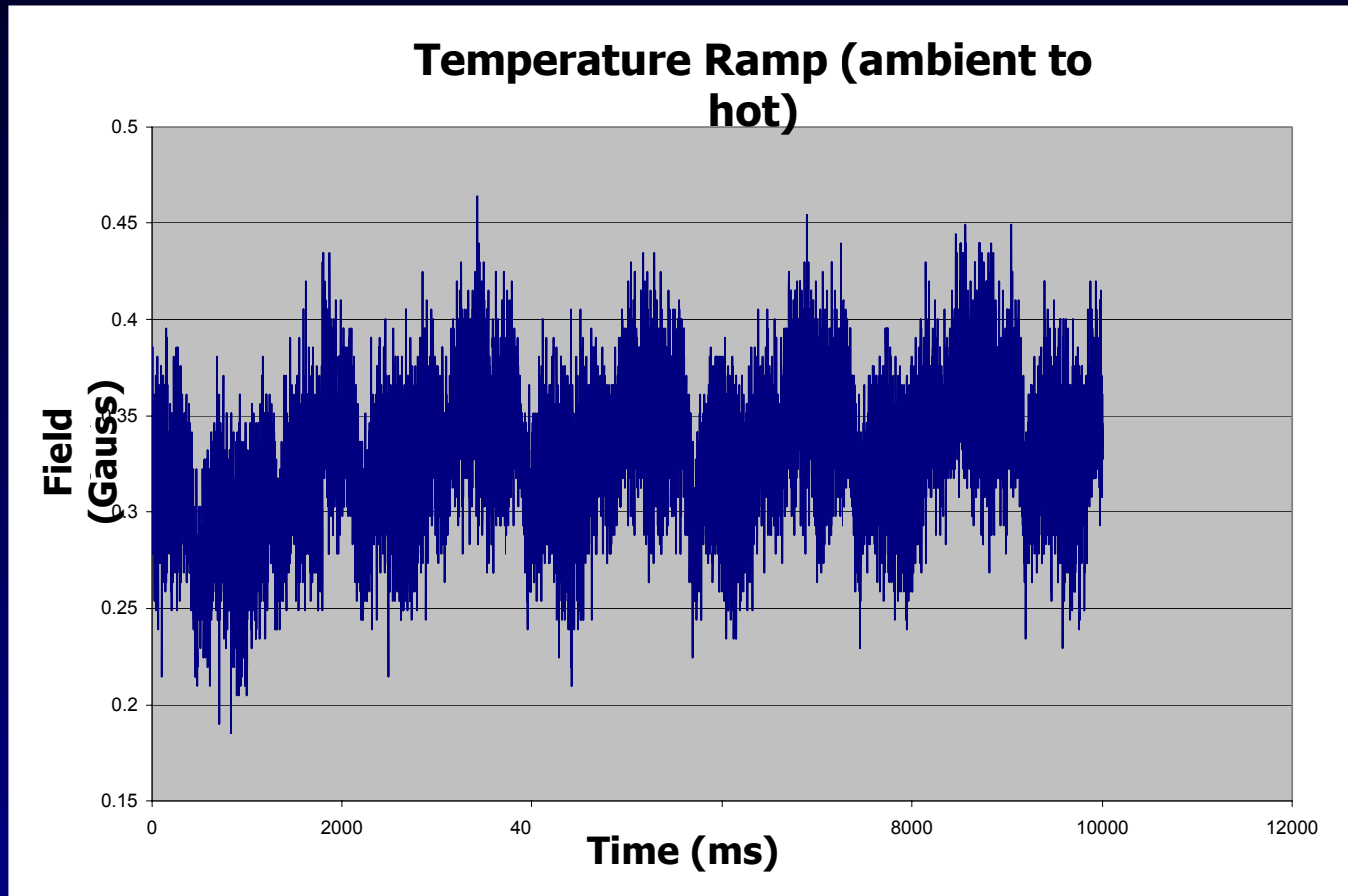


Y MOTION SLOW SCAN



TEMPERATURE TRANSITION ANALYSIS

- Initial Transition (10 Seconds) Ambient to Hot



DYNAMIC RESULTS

Measurement	MIN	AVE	MAX	IMPACT
Zeroing		0.04		Noisy – Needs Improvement
Z - 5, 10, 15 mils	----	----	----	OK – Negligible
Z - 50 mils	-1.32	-1.15	-1.09	Shield
Z – 200 mils	-1.48	-1.23	-1.00	<u>Shield</u>
X-Slow Scan	-1.30	-1.08	-0.89	OK
X-Fast Scan	-1.42	-1.22	-1.07	OK
Y Scan	-1.38	----	-1.03	OK, Delta 0.18,
Temp	0.17	0.32	0.47	OK

Spec < 5 G for Dynamic

FIELD CONTAINMENT STEPS

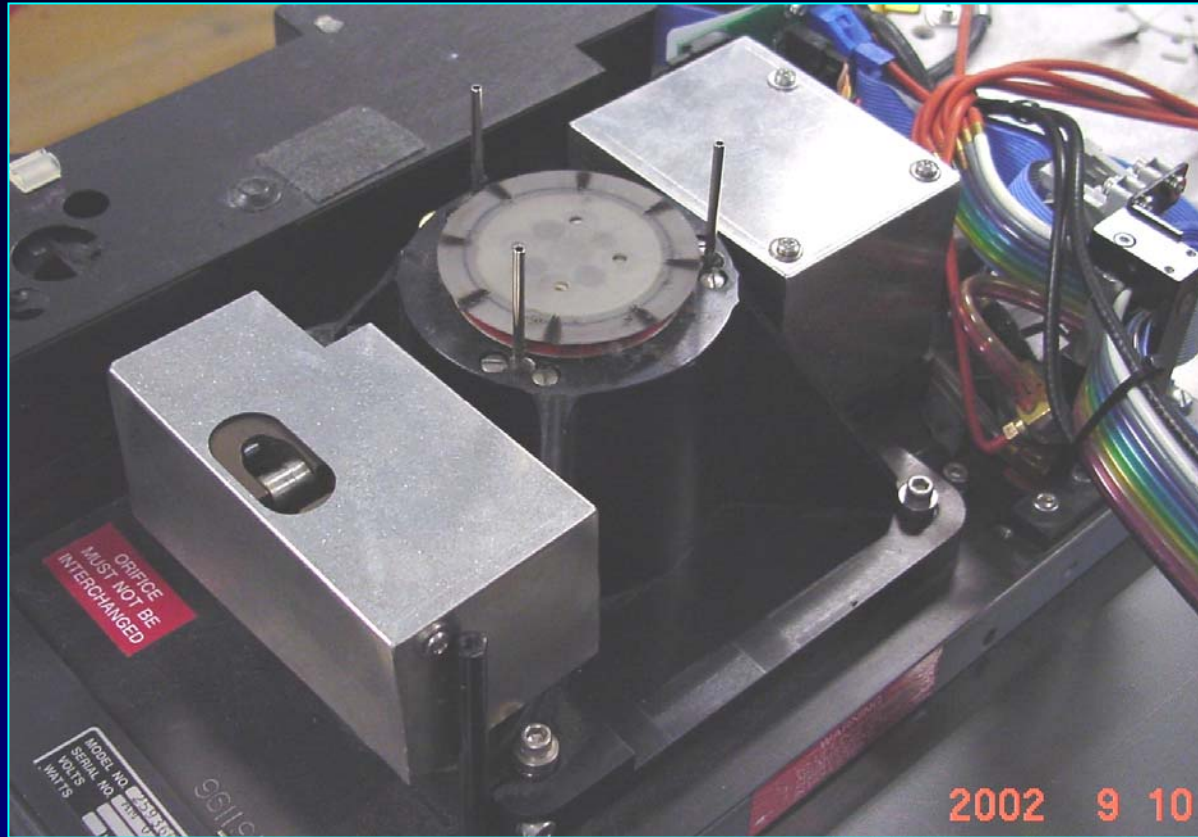
- Retrofitted Magnetic Shielding Kits
 - Replaced Shafts / Pins With Non-magnetic Materials
 - Designed Shields for Containment
 - Repositioned Components

- Improved Metrology –
 - Reduced Noisy Measurements
 - Improved Gaussmeters, Probes, and Sampling Jigs

- Completed Measurement Matrix

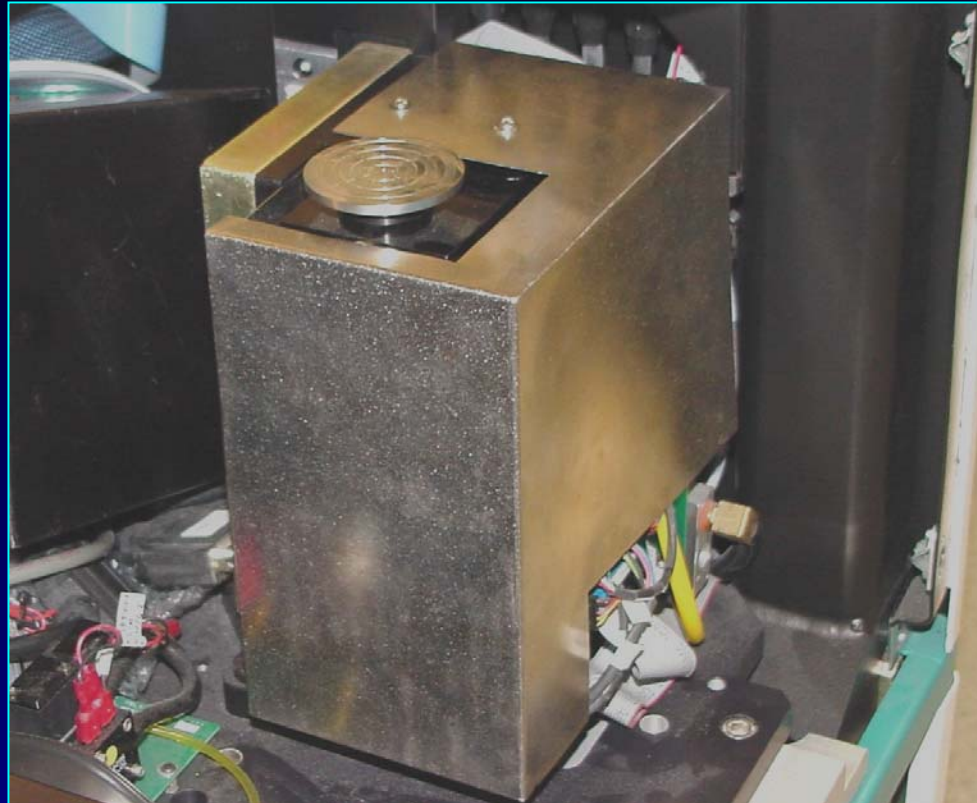
FORCER SHIELDS

Fully Assembled Theta and Z-motor Shield

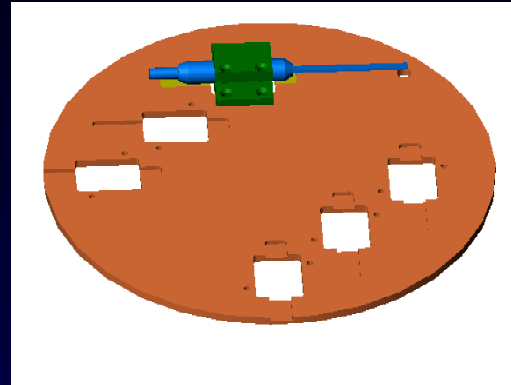


PRE-ALIGNER SHIELDS

Pre-Aligner Shield

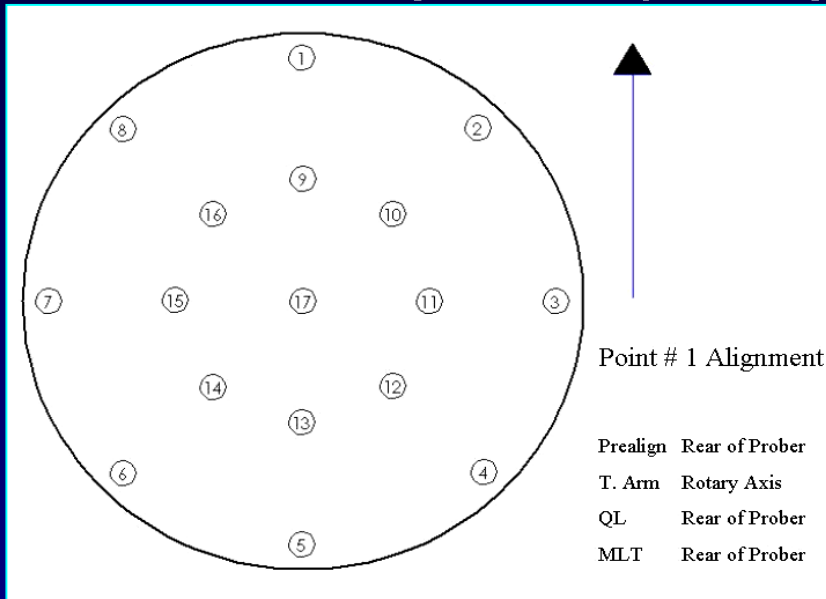


STATIC SAMPLING POINTS

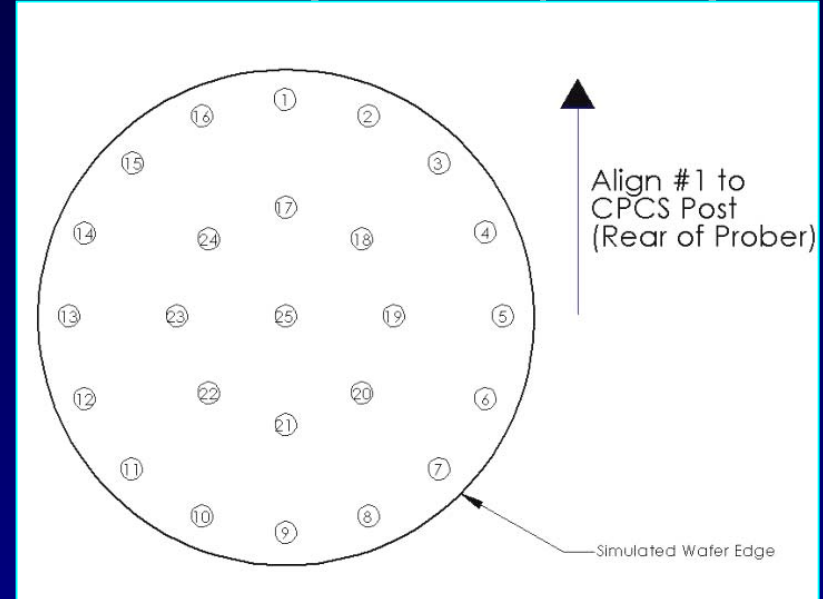


**SIMULATED
WAFER**

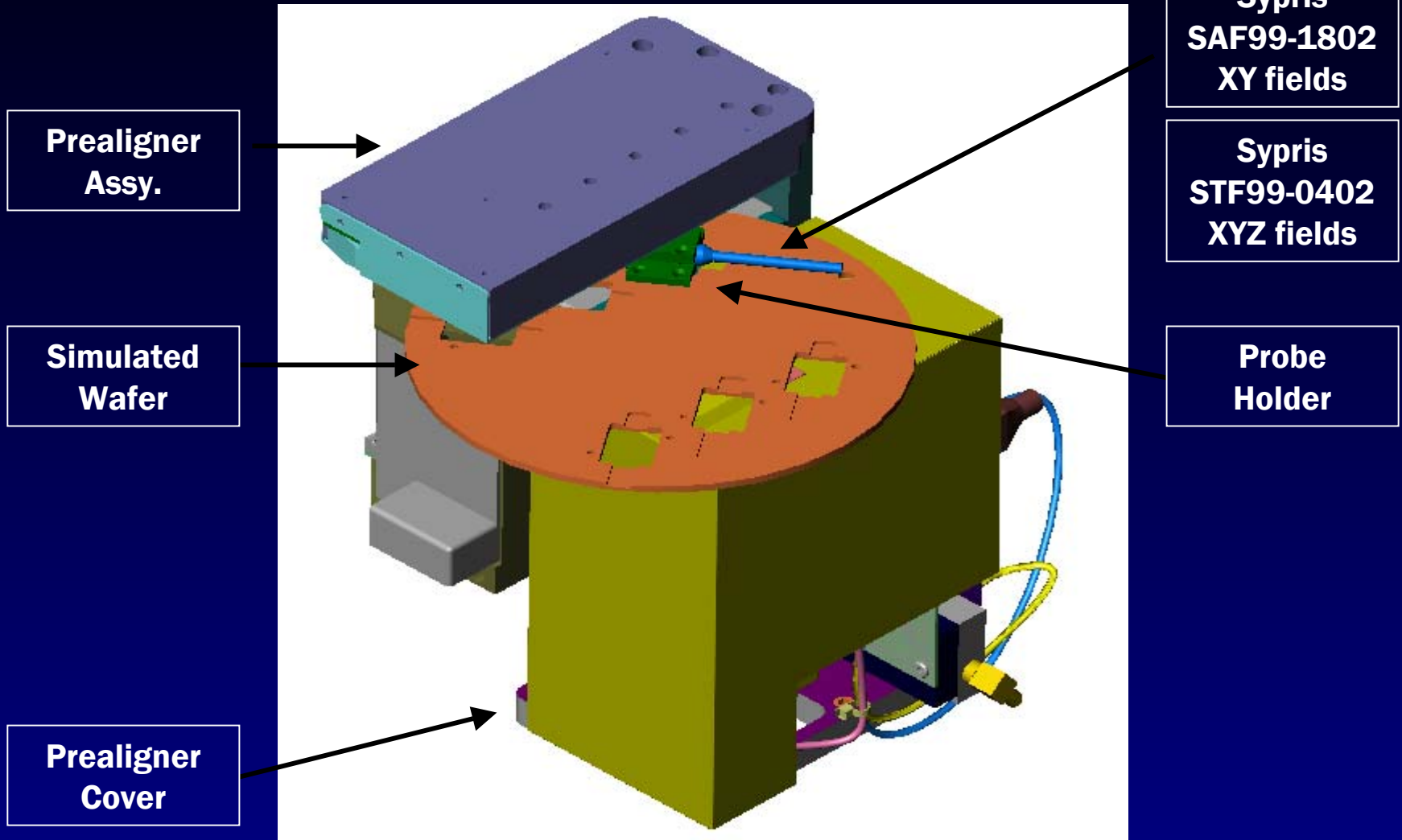
PREALIGNER (17 test points)



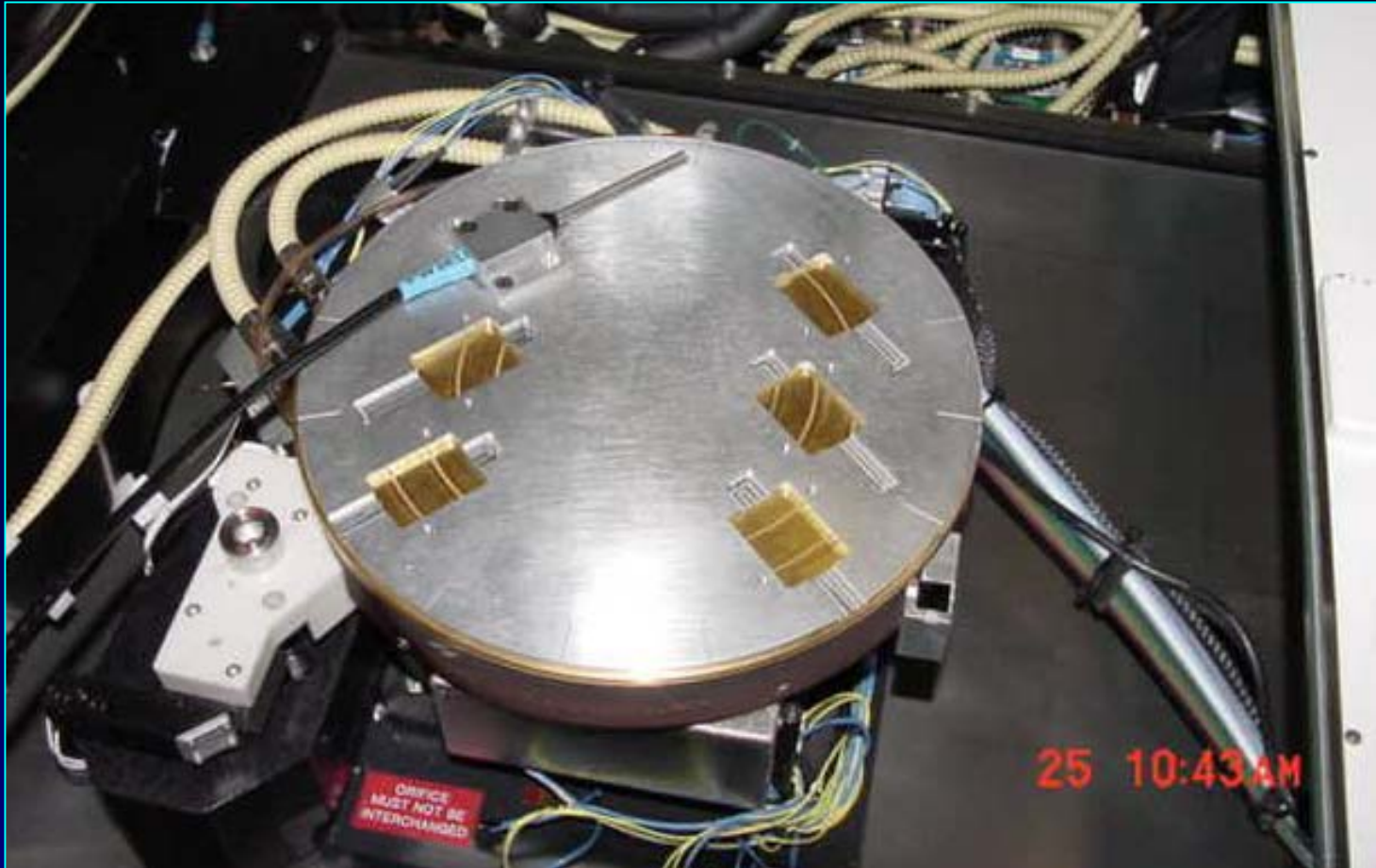
CHUCK (25 test points)



TEST FIXTURE



CHUCK FORCER POSITION



STATIC FIELD - CHUCK

- Measured (X, Y, and Z Axes)
 - Field Magnitude Is the Resultant Vector:

$$B = \sqrt{B_x^2 + B_y^2 + B_z^2}$$

- Results:
 - 1st Pass – Original Pins – 2.6 G Maximum
 - Pins Coupled Z, θ Motors to Wafer Surface
 - Replaced Pins With Non-magnetic Composition
 - 2nd Pass – SS 304 Pins – 1.84 G Maximum
 - 3rd Pass – New Mat'l Pins – 1.18 G Maximum
 - 4th Pass – Add Shields < 0.6 G Maximum

PIN MATERIAL EXPERIMENT

ss 304 pins (2nd Gen)

	1	2	3
Bx	0.55	-0.24	0.08
By	0.70	0.46	1.00
Bz	1.24	1.76	-0.30
B	1.53	1.84	1.05

Coupling Impact

New Pins (3rd Gen)

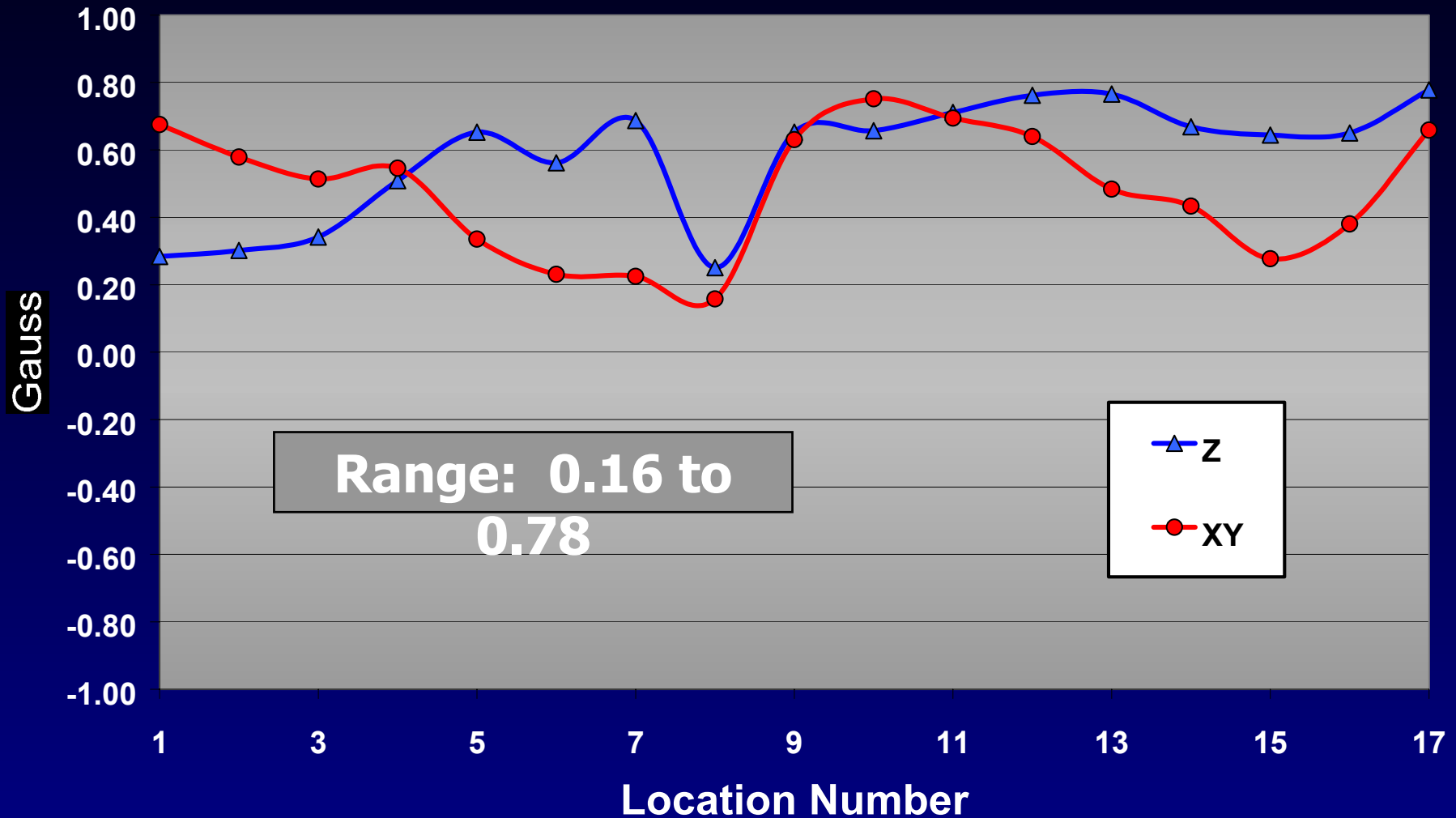
	1	2	3
Bx	0.28	0.37	0.06
By	0.33	0.48	0.70
Bz	0.25	0.64	-0.95
B	0.50	0.88	1.18

None Z- θ Z- θ

- Decision:
 - Pins alone don't meet spec, shield Z-theta motors
 - After Shielding: Wafer Plane < 0.6 G, Meets Spec !

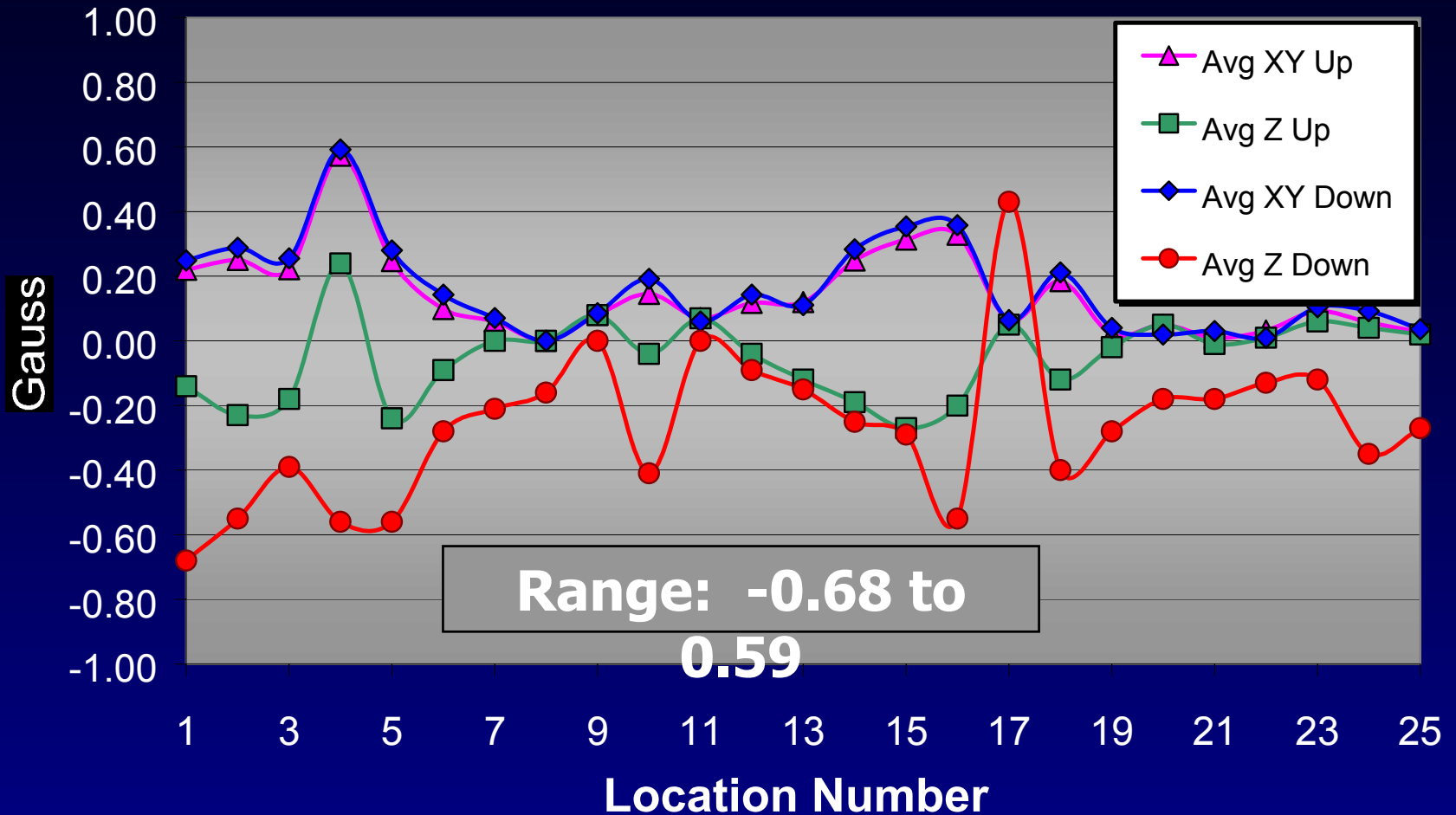
PRE-ALIGNER

4090 μ Pre-aligner XY and Z Fields



FORCER – PROBE AREA

4090 μ Probe Area XY And Z Averages
at Chuck Up And Down Position



MATERIAL HANDLER

- **Static Analysis**
 - (measured over wafer surface)

Site	Before, Max	After, Max
Chuck	8.0	0.6
Quick Loader	0.5	0.5
Transfer arm	0.5	0.5
Pre-aligner	1.3	0.8
Lift pins	8.0	0.5

CONCLUSION / SUMMARY

- New Memory – New Requirements
- MRAM Advantages
 - Target applications - cellular phones, portable devices, and personal computers.
 - Instant-on computing, indefinite standby without power.
- Test Challenges
 - Accurate magnetic measurements
 - Control of stray magnetic fields

APPRECIATION

- **Electroglas**
 - Steve Lugosi
 - Larry Hendler
 - Robert Bergan
 - Hardip Singh

- **Test Point Software**
 - Larry Hendler

- **Cypress - SMS**
 - Narayan Pirohit
 - Fred Jenne